

# INTERNATIONAL SEARCH REPORT

International Application No  
PCT/FR2004/002779

<b>A. CLASSIFICATION OF SUBJECT MATTER</b> IPC 7 H01L21/762		
According to International Patent Classification (IPC) or to both national classification and IPC		
<b>B. FIELDS SEARCHED</b> Minimum documentation searched (classification system followed by classification symbols) IPC 7 H01L		
Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched		
Electronic data base consulted during the International search (name of data base and, where practical, search terms used) EPO-internal, WPI Data, INSPEC, PAJ		
<b>C. DOCUMENTS CONSIDERED TO BE RELEVANT</b>		
Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	WO 00/63965 A (SILICON GENESIS CORPORATION; KANG, SIEN, G; MALIK, IGOR, J) 26 October 2000 (2000-10-26)	1-19, 24-33
Y	the whole document	20-23
X	US 2003/077885 A1 (ASPAR BERNARD ET AL) 24 April 2003 (2003-04-24)	1-8, 16-19, 24-33
A	page 4, paragraph 46 - page 4, paragraph 55	20-23
A	page 6, paragraph 81 - page 6, paragraph 83	9-15
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<input checked="" type="checkbox"/> Further documents are listed in the continuation of box C. <input checked="" type="checkbox"/> Patent family members are listed in annex.		
* Special categories of cited documents : 'A' document defining the general state of the art which is not considered to be of particular relevance 'E' earlier document but published on or after the international filing date 'L' document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified) 'O' document referring to an oral disclosure, use, exhibition or other means 'P' document published prior to the international filing date but later than the priority date claimed 'T' later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention 'X' document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone 'Y' document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art. '&' document member of the same patent family		
Date of the actual completion of the international search 23 March 2005		Date of mailing of the international search report 05/04/2005
Name and mailing address of the ISA European Patent Office, P.B. 5818 Patentlaan 2 NL - 2280 HV Rijswijk Tel. (+31-70) 340-2040, Tx. 31 651 epo nl, Fax: (+31-70) 340-3016		Authorized officer Hedouin, M

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## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
Y	AGARWAL A ET AL: "EFFICIENT PRODUCTION OF SILICON-ON-INSULATOR FILMS BY CO-IMPLANTATION OF HE+ WITH H+" APPLIED PHYSICS LETTERS, AMERICAN INSTITUTE OF PHYSICS, NEW YORK, US, vol. 72, no. 9, 2 March 1998 (1998-03-02), pages 1086-1088, XP000742819 ISSN: 0003-6951 the whole document	20-23
A	US 2002/025604 A1 (TIWARI SANDIP) 28 February 2002 (2002-02-28) page 1, paragraph 12 - page 2, paragraph 15; figures 1-6	1-12,15, 17,20-24
A	US 6 593 212 B1 (HOBART KARL D ET AL) 15 July 2003 (2003-07-15) column 4, line 65 - column 5, line 44; figures 1a-1c,10-11b	1-24
A	EP 0 994 503 A (COMMISSARIAT ENERGIE ATOMIQUE) 19 April 2000 (2000-04-19) column 9, paragraph 42 - column 9, paragraph 43	1-5

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Information on patent family members

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